	Туре	L #	Hits	Search Text	DBs	Time Stamp	Comment
1	BRS	L1			USPAT; US-PG PUB; EPO; JPO; DERWE NT; IBM_T DB	2004/10/0 9 13:54	
2	BRS	L2	926	probe\$1 near25 actuator\$1 near25 mov\$3	; 	2004/10/0 9 13:55	
3	BRS	L3	8 4	probe\$1 near25 actuator\$1 near25 mov\$3 near25 perpendicular	USPAT; US-PG PUB; EPO; JPO; DERWE NT; IBM_T DB	2004/10/0 9 14:38	

	Туре	L #	Hits	Search Text	DBs	Time Stamp	Comment
4	BRS	L4	14753	array near5 probes	USPAT; US-PG PUB; EPO; JPO; DERWE NT; IBM_T DB	2004/10/0 9 14:38	
5	BRS	L5	1513	(array near5 probes) near15 (dimensional)		2004/10/0 9 14:39	
6.	BRS	L6	774	near15		2004/10/0 9 14:39	

	Туре	L #	Hits	Search Text	DBs	Time Stamp	Comment
7	BRS	L7	21	(array near5 probes) near15 (two-dimensional) near15		2004/10/0 9 14:44	
8	BRS	L8	1	(probes near chip)	· TDA	2004/10/0 9 14:44	
9	BRS	L9	1	(probe near chip) near15 (two-dimensional) near15 (one-dimensional)	USPAT; US-PG PUB; EPO; JPO; DERWE NT; IBM_T DB	2004/10/0 9 14:45	

	Туре	L #	Hits	Search Text	DBs	Time Stamp	Comment
10	BRS	L10	67	(probe\$1) near15 (two-dimensional) near15 (one-dimensional)	USPAT; US-PG PUB; EPO; JPO; DERWE NT; IBM_T DB	2004/10/0 9 16:30	
11	BRS	L11	3	(probe near chip) near15 (two-dimensional)		2004/10/0 9 16:13	
12	BRS	L12	13	(probe near chip) near15 (dimension)	USPAT; US-PG PUB; EPO; JPO; DERWE NT; IBM_T DB	2004/10/0 9 16:13	

	Туре	L #	Hits	Search Text	DBs	Time Stamp	Comment
13	BRS	L13	8	(probe near chip) near15 (\$-dimensional)	USPAT; US-PG PUB; EPO; JPO; DERWE NT; IBM_T DB	2004/10/0 9 16:14	
14	BRS	L14	289	(probe\$1) near15 (one-dimensional)	USPAT; US-PG PUB; EPO; JPO; DERWE NT; IBM_T DB	2004/10/0 9 16:15	

	U	1	Document ID	Title	Current OR	Pages
1				Parallel, individually addressable probes for nanolithography	324/765	15
2	⊠		<u>:</u>	Method for making probe support and apparatus used for the method	435/6	47
3			US 5824481 A	DNA analyzing method	435/6	16
4			US 5650274 A	DNA analyzing method	435/6	16
5			JP 11153427 A	COORDINATES MEASURING MACHINE		4 6
6	×		JP 09251319 A	POSITIONING UNIT FOR FINE POSITIONING DEVICE		8
7	\boxtimes		JP 06051831 A	TWO-DIMENSIONAL POSITION ADJUSTING DEVICE		4
8	\boxtimes		US 20040119490 A	Pattern forming apparatus for e.g. Dip Pen Nanolithography, comprises probe chip having probe array, first actuator for moving the probe chip, second actuators for selectively raising or lowering each probe tip, and actuating source		15